

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : FRANK-MICHAEL KAMM ET AL.

Filed : CONCURRENTLY HERewith

Title : REFLECTIVE MIRROR FOR LITHOGRAPHIC EXPOSURE AND
PRODUCTION METHOD

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In accordance with 37 C.F.R. 1.98 copies of the following patents and/or publications are submitted herewith:

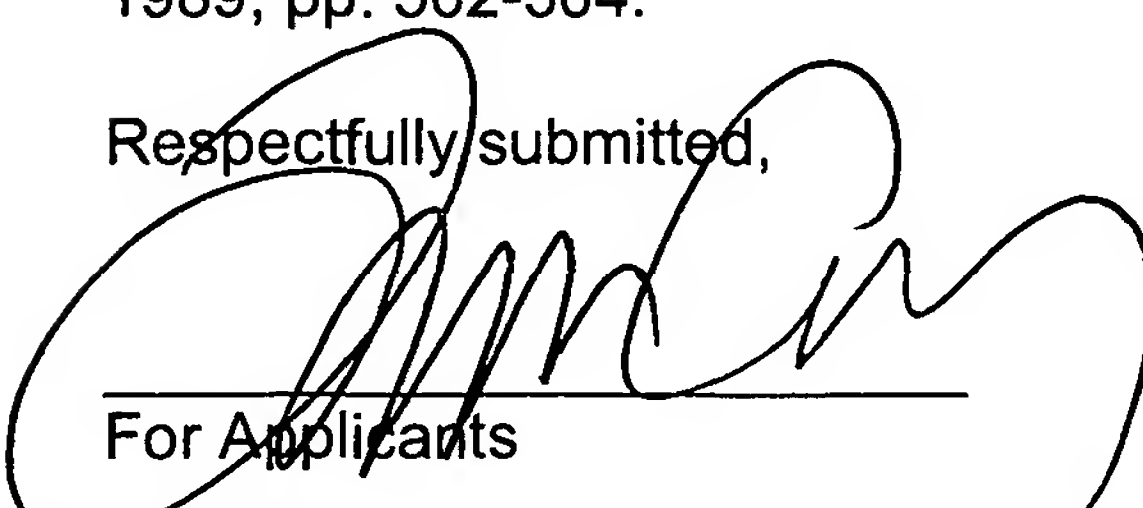
European Patent Application EP 1 065 532 A2 (Singh), dated January 3, 2001;

Morita, M. et al.: "Native Oxide Growth on Silicon Surface in Wet Ambient", Extended Abstract of the 22nd Conference on Solid State Devices and Materials, 1990, pp. 1063-1066;

Yasaka, T. et al.: "Layer-By-Layer Oxidation of Silicon", Materials Research Society Proc., Vol. 222, 1991, pp. 225-230;

Morita, M. et al.: "Control Factor of Native Oxide Growth on Silicon Surface in Air or in Ultrapure Water", Appl. Phys. Lett. 55 (6), American Institute of Physics, August 7, 1989, pp. 562-564.

Respectfully submitted,


For Applicants

LAURENCE A. GREENBERG
REG. NO. 29,308

Date: August 1, 2003

Lerner and Greenberg, P.A.
Post Office Box 2480
Hollywood, FL 33022-2480
Tel: (954) 925-1100
Fax: (954) 925-1101

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FORM PTO-1449 (SUBSTITUTE) U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE INFORMATION DISCLOSURE STATEMENT BY APPLICANT (37 CFR 1.98(b))				Attorney Docket No.: P2002,0645 Appl. No.: <hr/> Applicant: FRANK-MICHAEL KAMM ET AL. <hr/> Filing Date: August 1, 2003 Group Art Unit:			
EXAMINER INITIALS		PATENT NO.	DATE	PATENTEE	CLASS	SUB CLASS	FILING DATE
	A						
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FOREIGN PATENT DOCUMENT							
		DOCUMENT NO.	DATE	COUNTRY	CLASS	SUB CLASS	TRANSL. YES NO
	J	1 065 532 A2	1/3/01	Europe			
	K						
	L						
	M						
	N						
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)							
		Morita, M. et al.: "Native Oxide Growth on Silicon Surface in Wet Ambient", Extended Abstract of the 22 nd Conference on Solid State Devices and Materials, 1990, pp. 1063-1066					
		Yasaka, T. et al.: "Layer-By-Layer Oxidation of Silicon", Materials Research Society Proc., Vol. 222, 1991, pp. 225-230					
EXAMINER				DATE CONSIDERED			

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EXAMINER				DATE CONSIDERED			